PhDs

- Evangelia Tegou (General Chemical Laboratories)
 Physical chemistry of polymers in patterning processes for IC fabrication: The case of silylation and plasma development (1999)
- George Kokkoris (NCSR "Demokritos")
 Integrated simulation of topography evolution during plasma etching of micro and nanostructrures (2004)
- Nikolaos Vourdas
 Oxygen plasma etching, surface modification and nanotexturing of PMMA: Study of mechanisms and applications in PMMA microfluidic devices (2007)